

AMENDMENTS TO THE SPECIFICATION:

At page 1, please amend the title appearing at lines 3-6 as follows:

METHOD OF MANUFACTURING ELECTRONIC DEVICE,
ELECTRON SOURCE SUBSTRATE, AND IMAGE FORMING APPARATUS, AND
APPARATUS FOR MANUFACTURING ELECTRONIC DEVICE AND ELECTRON
SOURCE SUBSTRATE / ELECTRON-EMITTING DEVICE USING INK-JET
DISCHARGE DEVICE

Please amend the Abstract appearing at page 48, lines 2-14 as follows:

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An electronic electron-emitting device manufacturing apparatus includes
method comprising a gas removal means for step of removing a gas dissolved in a liquid
containing the a formation material of a member constituting an electronic device an
electroconductive film in which an electron emitting area is to be formed, a temperature
adjusting step of adjusting a temperature of the liquid from which the gas is removed, and
a droplet discharge means for step of discharging droplets of which the temperature is
adjusted the liquid by droplet discharge means in an ink jet manner, and a means for while
controlling the relative positions of the droplet discharge means and a substrate on which
the electronic device electroconductive film in which the electron-emitting area is to be
formed is formed. The droplets are thereby applied to a predetermined position on the

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substrate. The gas removal means includes a closed vessel filled with membrane formed from a semi-transmitting film capable of transmitting a gas, and a vacuum unit for evacuating the closed vessel.
